Lecture 8:

# **Comb Resonator Design (4)** - Intro. to Fluidic Dynamics (Damping) -

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# **Two Types of Fluids**

- Liquid : molecules are free to change position but are bound by cohesive forces. (fixed volume)
- **Gas** : molecules are unrestricted. (no shape or volume) ٠





# **Methods of Analysis**

- System •
  - It is defined as a fixed, identifiable quantities of mass.
  - No mass crosses the system boundary.
  - Heat and work may cross the boundary of the system.





# Methods of Analysis (cont'd)

- Control volume
  - An arbitrary volume in space through which fluid flows.
- Control surface
  - The geometric boundary of the control volume.





#### Mean Free Path

- Mean free path ( $\lambda$ ) •
  - A distance that the molecule travels before it reacts with another molecules.



 $\lambda = v \cdot t$ 

v: average velocity

of the molecule

*t* : *mean free time* 

#### Target molecule

mean free path :  $\lambda [m] = \frac{5 \times 10^{-5}}{P [Torr]}$  (in air, at room temperature)

ex) 
$$P = 1 atm \rightarrow \lambda = 60 nm$$



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# Viscosity

#### Absolute viscosity (µ) •

- The shearing stress ( $\tau$ ) and rate of shearing strain (du/dy) can be related with a relationship of the form.



$$\tau = \mu \frac{du}{dy}$$
  

$$\mu: \text{ viscosity (absolute)}$$
  

$$[\mu] = (N/m^2) \cdot (s)$$

f =force , u=velocity, A= area of the plate, d =distance between the plates, T= shear stress



# Viscosity (cont'd)

Kinetic viscosity (V)•

$$v = \frac{\mu}{\rho} : [v] = m^2 / s$$

 $\mu$ : absolute viscosity,  $\rho$ : density

- For gases, kinetic viscosity increases with temperature, whereas for liquids, kinetic viscosity decreases with increasing temperature.



# **Fluid Motions**

#### Viscous flow

- The shear stress gives rise to change the velocity of the fluid at the interface between the solid and fluid.
- Inviscid flow
  - The effect of shear stress is so small as to be negligible.





# **Dissipation in Fluid Flow**

- **Dissipated energy** (D) ٠
  - Work is required to move the plate, but this work is not stored as potential or kinetic energy in the plate or fluid.
  - The differential volume is deformed by the shear force.
  - The work done on the differential volume.

$$D = \tau \cdot du_x dx dz$$





# **Stress Field**

#### • Surface force

– It acts on the boundaries of a medium through direct contact. (pressure, stress etc)

#### **Body force** ٠

- Forces developed without physical contact, and distributed over the volume of fluid. (gravitational force etc)



#### **Momentum Equation**

Forces acting on a fluid particle •



< Surface forces in the x direction on a fluid element>



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#### Momentum Equation (cont'd)

• Surface force (Fs) for x-axis

$$dF_{sx} = (\sigma_{xx} + \frac{\partial \sigma_{xx}}{\partial x} \cdot \frac{dx}{2}) dy dz - (\sigma_{xx} + \frac{\partial \sigma_{xx}}{\partial x} \cdot \frac{dx}{2}) dy dz + (\tau_{yx} + \frac{\partial \tau_{yx}}{\partial y} \cdot \frac{dy}{2}) dx dz - (\tau_{yx} + \frac{\partial \tau_{yx}}{\partial y} \cdot \frac{dy}{2}) dx dz + (\tau_{zx} + \frac{\partial \tau_{zx}}{\partial z} \cdot \frac{dz}{2}) dx dy - (\tau_{zx} + \frac{\partial \tau_{zx}}{\partial z} \cdot \frac{dz}{2}) dx dy = (\frac{\partial \sigma_{xx}}{\partial x} + \frac{\partial \tau_{yx}}{\partial y} + \frac{\partial \tau_{yx}}{\partial y}) dx dy dz \quad \dots \dots \dots \dots \dots (1)$$

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### Momentum Equation (cont'd)

Body force (F<sub>B</sub>) for x-axis : gravity ٠

Then, the total force in x direction ((1)+(2))

$$dF_{x} = dF_{sx} + dF_{Bx}$$

$$= (\rho g_{x} + \frac{\partial \sigma_{xx}}{\partial x} + \frac{\partial \tau_{yx}}{\partial y} + \frac{\partial \tau_{zx}}{\partial z})dxdydz \dots (3)$$
similarly,  $dF_{y} = (\rho g_{y} + \frac{\partial \sigma_{yy}}{\partial y} + \frac{\partial \tau_{xy}}{\partial x} + \frac{\partial \tau_{zy}}{\partial z})dxdydz$ 

$$dF_{z} = (\rho g_{z} + \frac{\partial \sigma_{zz}}{\partial z} + \frac{\partial \tau_{xz}}{\partial x} + \frac{\partial \tau_{yz}}{\partial y})dxdydz$$



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### **Differential Momentum Equation**

From the Newton's 2<sup>nd</sup> law of motion  $d\overline{F} = dm \frac{dv}{dv}$  $(\rho g_x + \frac{\partial \sigma_{xx}}{\partial r} + \frac{\partial \tau_{yx}}{\partial r} + \frac{\partial \tau_{zx}}{\partial r})dxdydz$  $= \rho dx dy dz \left(\frac{\partial u}{\partial t} + u \frac{\partial u}{\partial y} + v \frac{\partial u}{\partial y} + w \frac{\partial u}{\partial z}\right)$  $\therefore \rho g_x + \frac{\partial \sigma_{xx}}{\partial x} + \frac{\partial \tau_{yx}}{\partial y} + \frac{\partial \tau_{zx}}{\partial z} = \rho (\frac{\partial u}{\partial t} + u \frac{\partial u}{\partial x} + v \frac{\partial u}{\partial y} + w \frac{\partial u}{\partial z})$ 

 $\rightarrow$  Similarly, we can have y and z differential equation of motion.



### **Navier-Stokes Equation**

#### Newtonian fluid

Fluids for which the shearing stress is linearly related to the rate of the shearing strain.

 $\tau_{xy} = \tau_{yz} = \mu \left(\frac{\partial v}{\partial x} + \frac{\partial u}{\partial y}\right), \qquad \sigma_{xx} = -\rho - \frac{2}{3}\mu \nabla \cdot \overline{v} + 2\mu \frac{\partial u}{\partial x}$  $\tau_{yz} = \tau_{zy} = \mu (\frac{\partial v}{\partial z} + \frac{\partial w}{\partial y}), \qquad \sigma_{yy} = -\rho - \frac{2}{3}\mu \nabla \cdot \overline{v} + 2\mu \frac{\partial v}{\partial y}$  $\tau_{zx} = \tau_{xz} = \mu \left(\frac{\partial w}{\partial x} + \frac{\partial u}{\partial z}\right), \qquad \sigma_{zz} = -\rho - \frac{2}{3}\mu \nabla \cdot \overline{v} + 2\mu \frac{\partial w}{\partial z}$ Navier - stokes Equation x - momentum Equation  $\rho \frac{\sigma u}{\sigma t} = \rho g x - \frac{\partial p}{\partial r} + \frac{\partial}{\partial r} \left\{ \mu \left( 2 \frac{d u}{d r} - \frac{2}{3} \nabla \cdot \overline{v} \right) \right\}$  $+\frac{\partial}{\partial y}\left\{\mu(\frac{du}{dy}-\frac{\partial v}{\partial x})\right\}+\frac{\partial}{\partial z}\left\{\mu(\frac{dw}{dx}-\frac{\partial u}{\partial z})\right\}$ 



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### Navier-Stokes Equation (cont'd)

- **Navier-Stokes Equation** •
  - Equation of motion governing fluid behavior

$$\rho \frac{\partial u}{\partial t} + (\nabla \cdot u)u = \rho g - \nabla (p) + \mu \nabla^2 u$$
  

$$\rho : mass \ density \ \mu : absolute \ vis \cos ity$$
  

$$p : pressure \ u : velocity \ g : gravity$$

[Ref.] Bruce R. Munson "Fundamentals of Fluid Mechanics", 2<sup>nd</sup> ed.



# Navier-Stokes Equation (cont'd)

- Apply the Navier-Stokes equation to some special cases
  - Couette flow
  - Stokes flow



#### **Couette Flow**

#### **Couette flow** •

- We obtain a linear velocity profile for the fluid film underneath the plate, as shown in Figure.



[Ref.] Y.-H. Cho, A. P. Pisano, and R. T. Howe, "Viscous damping model for laterally oscillating microstructures," IEEE JMEMS, Vol. 3, No. 2, pp. 81-87, 1994.

X. Zhang and W. C. Tang, "Viscous air damping in laterally driven microresonators," MEMS 1994, pp. 199-204, 1994



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### Couette Flow (cont'd)

- **Navier- Stokes Equation** :  $\rho \frac{\partial u}{\partial t} + (\nabla \cdot u)u = \rho g \nabla (p) + \mu \nabla^2 u$ ٠
  - Neglecting the time dependent term, **du/dt=0**. And we assume no pressure gradient, **dp/dx=0**. Then we have

$$\nabla^2 u = 0 \xrightarrow{1-D} \frac{\partial^2 u_x(y)}{\partial y^2} = 0$$

No-slip boundary conditions (**zero velocity** at the surface of the stationary plate), than we have

$$u_{x} = \frac{y}{d}u_{0}$$

**Dissipated energy :** 

$$D = \frac{\pi}{w} u_0^2 \left(\frac{\mu}{d}\right)$$



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### **Stokes Flow**

#### **Stokes flow**

The steady state velocity profile, u(y,t), in the fluid is governed by time term of the Navier-Stokes Equation.



[Ref.] Y.-H. Cho, A. P. Pisano, and R. T. Howe, "Viscous damping model for laterally oscillating microstructures," IEEE JMEMS, Vol. 3, No. 2, pp. 81-87, 1994.

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### Stokes Flow (cont'd)

**Navier-Stokes Equation** :  $\rho \frac{\partial u}{\partial t} + (\nabla \cdot u)u = \rho g - \nabla (p) + \mu \nabla^2 u$ •

- And we assume **no pressure gradient**. Then we have

$$\frac{\partial u}{\partial t} = \frac{\mu}{\rho} \frac{\partial^2 u}{\partial y^2}, \quad \frac{\partial u}{\partial t} = v \frac{\partial^2 u}{\partial y^2} \quad v: kinetic \ vis \cos ity$$

- No-slip boundary conditions (i.e., **zero velocity** at the surface of the stationary plate, Than we have

$$u_x = u_0 e^{j(\beta y - wt)}$$
 where  $\beta = \sqrt{w/2v}$ 

- Dissipated energy: 
$$D = \frac{\pi}{w} u_0^2 (\mu \beta \frac{\sinh 2\beta d + \sin 2\beta d}{\cosh 2\beta d - \cos 2\beta d})$$



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# Squeeze Film

#### Squeeze-film damping

- **Dissipated force**
- Vertical Motion of upper plate relative to fixed bottom plate with viscous fluid between plates
- Viscous drag during flow creates dissipative force on plate opposing motion





# Squeeze Film (cont'd)

- Assumption
  - **No pressure gradient** transverse to the plate
  - Gap, h, is much smaller than the lateral dimensions of plate.





## **Quality Factor Analysis**



- Stokes flow model  $\rightarrow$  Qd, Qc
- Squeeze film model  $\rightarrow$  Qs



## Quality Factor Analysis (cont'd)

- **Damping Coefficient** & **Quality factor** ۲
  - System equation

$$F_{ext} = Mx'' + bx' + Kx$$

$$x'' + \frac{b}{M}x' + \frac{K}{M}x = x'' + 2\zeta\omega_n + {\omega_n}^2$$

$$- \text{ Damping ratio}: \ \zeta = \frac{1}{2Q}, \text{ Natural frequency}: \ \omega_n = \sqrt{\frac{K}{M}}$$

- Damping coefficient : 
$$b = 2M \zeta \omega_n = \frac{\sqrt{MK}}{Q}$$

- Quality factor : 
$$Q = \frac{\sqrt{MK}}{b}$$



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# Quality Factor Analysis (cont'd)

- Parameter (1 atm, at room temperature)
  - Natural frequency : f = 5.071 kHz
  - Absolute viscosity :  $\mu$ = 1.8 x 10<sup>-5</sup> kg/m·sec
  - Kinetic viscosity :  $v = 1.5 \times 10^{-5} \text{ m}^2/\text{sec}$
  - Density of silicon : 2330 kg/m<sup>3</sup>
  - Distance of inter-plate (sacrificial gap)  $d=20 \ \mu m$
  - Distance of inter-plate (between structure and cap)  $h=150 \mu m$
  - Distance of inter-combs :  $dc=2 \mu m$
  - Mass: 42 μg
  - Spring stiffness: 137.0 N/m



# **Stokes Flow Model (Qd)**



$$put \ u = u_0 e^{i(\beta y \cdot wt)} \text{ where } \beta = \sqrt{\frac{w}{v}},$$

$$D = \frac{1}{w} \int_0^{2\pi} \tau_0 u d(wt) , \tau_0 = -\mu \frac{du}{dy} (frictional \ shear)$$

$$D = \frac{\pi}{w} u_0^2 \mu \beta (\frac{\sinh 2\beta y + \sin 2\beta y}{\cosh 2\beta y - \cos 2\beta y})$$

$$(a) \ 0 < y < d_1$$

$$D = \frac{\pi}{w} u_0^2 \mu \beta (\frac{\sinh 2\beta d + \sin 2\beta d}{\cosh 2\beta d - \cos 2\beta d})$$

$$Qd_1 = \frac{2\pi W}{AD} = \frac{1}{\mu A\beta} \sqrt{MK} (\frac{\cosh 2\beta d - \cos 2\beta d}{\sinh 2\beta d + \sin 2\beta d}) \dots (1)$$

$$W: \ strain \ energy, \ A: \ plate \ area, \ D: \ dissipate \ energy$$

$$(b) \ d_2 < y < d_3 \ h = d_3 - d_2$$

$$Qd_2 = \frac{2\pi W}{AD} = \frac{1}{\mu A\beta} \sqrt{MK} (\frac{\cosh 2\beta h - \cos 2\beta h}{\sinh 2\beta h + \sin 2\beta h}) \dots (2)$$

[Ref.] T. Y. Song, S. J. Park, Y. H. Park, D. H. Kwak, H. H. Ko, and D. I. Cho, "Quality Factor in Microgyroscopes," APCOT MNT 2004, pp. 916-920, 2004



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## **Stokes Flow Model (Qc)**



#### Oc between comb fingers



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## Squeeze Film Model (Qs)



$$F = \int_{-L/2}^{L/2} pwdx = \frac{\mu wL^3}{d^3} \frac{dh}{dt}$$
$$b = \frac{\mu wL^3}{d^3}$$
$$(d) Qs = \frac{d^3}{\mu wL^3} \sqrt{MK} \dots (4)$$



# **Quality Factor Analysis Results**

#### Quality factor versus viscosity



[Ref.] T. Y. Song, S. J. Park, Y. H. Park, D. H. Kwak, H. H. Ko, and D. I. Cho, "Quality Factor in Microgyroscopes," APCOT MNT 2004, pp. 916-920, 2004



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# Quality Factor Analysis Result (cont'd)



[Ref.] M. Bao, H. Yang, H. Yin, and Y. Snu "Energy transfer model for squeeze-film air damping in low vacuum," IOP JMM, Vol. 12, pp 341-346, 2002



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# Quality Factor Analysis Result (cont'd)



The Quality factor versus the pressure

	Sacrificial gap	Quality factor	Damping Coefficient (b)
P = 200mTorr	2 um	4.1 x 10 <sup>4</sup>	1.8 x 10 <sup>-6</sup>
P = 200mTorr	20 um	1.2 x 10 <sup>5</sup>	6.3 x 10 <sup>-7</sup>



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# Quality Factor Analysis Result (cont'd)





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